

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q64059

Shigeo ISHIKAWA

Appln. No.: 09/832,093

Group Art Unit: 2823

Confirmation No.: 8684

Examiner: Khiem D. Nguyen

Filed: April 11, 2001

For:

FILM FORMING METHOD IN WHICH FLOW RATE IS SWITCHED

RESPONSE UNDER 37 C.F.R. § 1.111

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated March 31, 2004, please consider the remarks on the accompanying pages.

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REMARKS